# **Model 1401 Depth Profiling Ion Source**



### **Design Features**

High current density 15 to 50 mA/cm<sup>2</sup> depending on spot size selected.

Unique ion source design for stable emission.

Dual tungsten filaments with typical filament life-time > 500 hours. Yttria coated iridium optional.

Replaceable beam trimming aperture with typical life-time > 500 hours.

All UHV compatible and etch resistant materials used in fabrication.

Differential pumping to minimize main chamber gas loading.

Gun is easily disassembled for maintenance.

Electrical connections and gas inlet located on a single flange for easier installation.

Preset extraction and condenser lens parameters (three spot size settings) for repeatable operation.

Integral beam current measurement.

Direct measurement of ion source pressure.

System and cable interlocks prevent energizing high voltage with poor vacuum or cable removed.

Power supply and raster generator in single  $5^{-1}/_4$  high 19 inch rack mount enclosure.

Digitally generated raster option for uniform etch profile.

Computer control option.

Optional ion source pressure regulation.

#### Guaranteed Performance: 5.0 keV kinetic energy Ar ions

Mode	Spot size (µms)	Beam Current	Current Density (mA/cm²)
Large Spot	400	20 μΑ	15
Small Spot	50	1μA	50



# **Engineering Specification**

Working Distance: 25 mm

Beam energy:  $\leq 5 \text{KeV}$  continuously variable

Raster Size: 4 x 4 mm (minimum)

Mounting Flange: 70 mm (2.75in) Conflat

Differential Pumping: 70 mm (2.75 in) Conflat

Supply Gas Inlet: 34 mm (1.33 in) Conflat

Source gases: He, Ne, Ar, Kr, Xe

Bake-out Temperature: 150 °C maximum

## **System Integration Details**

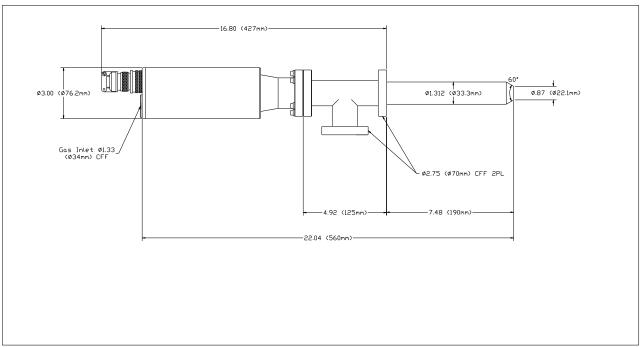
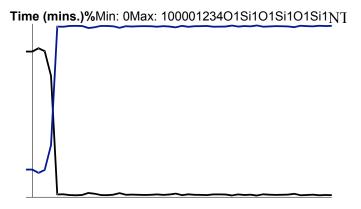
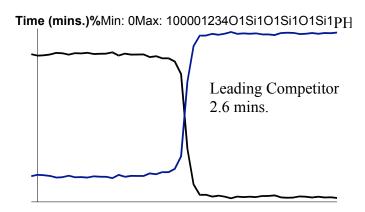


Fig. 1 Model 1401 Ion Gun, Outline Drawing



# **Etch Rate Comparison**

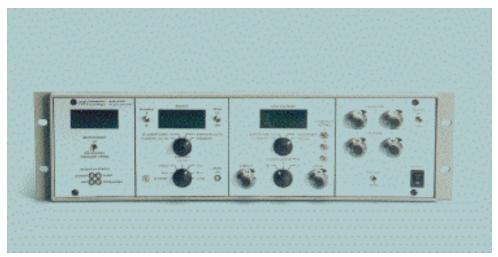




Depth Profiles taken through  $1000\sum$  of  $SiO_2$  on Si to demonstrate the advantage in etch rate of the NTI 1401 compared to a leading competitor.



#### Model 1401A Ion Gun Controller



#### **Controller Features**

Precise and stable lens voltages

Emission regulated electron impact current supply

Front panel raster controls with external programmability

Power interlocks for safety and equipment protection

Remote On/Off control for automated operation from external equipment

Raster compensation electronics to correct for changes in sample geometry and working distance Comprehensive front panel system parameter monitoring

### **Controller Specification**

Input Power: 115/220 volts AC auto-select operation. Fused at 3.3 Amperes. Beam Energy: 0 - 5000 volts switch mode supply continuously variable.

O/P current: 1 mA maximum. O/P capacitance: 0.0047 µF.

Condenser: 0 - 5000 volts switch mode supply continuously variable. O/P voltage scales

with Energy. O/P current: 1 mA maximum. O/P capacitance: 0.0047 μF

Objective Focus: 0 - 5000 volts switch mode supply continuously variable. O/P voltage scales with

Energy. O/P current: 1 mA maximum. O/P capacitance: 0.0047 μF

Filament Power: Emission regulated supply with front panel selectable filaments providing 5 volts @

5 Amp. maximum.

Electron Impact Internally adjustable accelerating voltage and emission current front panel metering.

Internally adjustable to 1500 volts.

Faraday Collector: Front panel momentary switch permits beam current monitoring through panel

mounted display.

Deflection: Variable bi-polar 350 volt dc supply for +X, -X, +Y and -Y deflection. Remaining

octupole elements are supplied from a resistive divider network.

Interlocks: HV cable disconnection turns off HV supplies.

Adjustable high pressure interlock switches off HV supplies in the event of system

overpressure.

System and Auxiliary interlocks provide total shutdown in the event of system or

auxiliary equipment failure.

Front Panel Monitoring: Digital panel meters provide precision monitoring of all critical parameters including;

lens voltages ( $4^{1}/_{2}$  digit), ion source pressure and beam current ( $3^{1}/_{2}$  digits), filament

current and voltage (3<sup>1</sup>/<sub>2</sub>digits), emission current (3<sup>1</sup>/<sub>2</sub>digits).

Chassis Dimensions: 483(w)x132.5(h)x435.4(d) mm. 19 inch rack-mountable desktop case 3U high.



Nonsequitur Technologies 900 SE Wilson Ave. Suite A Bend, OR 97702 Ph: 541-312-2410 Fax: 541-312-2412